

Title (en)
ABRASIVE SURFACE AND ARTICLE AND METHODS FOR MAKING THEM

Title (de)
SCHLEIFOBERFLÄCHE UND -ARTIKEL UND DEREN HERSTELLUNGSVERFAHREN

Title (fr)
SURFACE ET ARTICLE ABRASIFS ET LEURS PROCÉDES DE FABRICATION

Publication
EP 1237679 B1 20090401 (EN)

Application
EP 00986502 A 20001218

Priority
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• US 17215199 P 19991217

Abstract (en)
[origin: WO0143918A2] A method for making an abrasive material comprising a plurality of hard particles providing the abrasive quality distributed in a retaining matrix for holding the particles in place, the method comprising the steps of placing a mask having openings therein against a carrier capable of supporting a plurality of the particles, providing an affixing capability to an outer side of the mask remote from the carrier to which hard particles will adhere, applying a plurality of hard particles to the outer side of the mask so that a portion of the particles pass through the openings of the mask and form a pattern of the particles on the carrier corresponding to the openings of the mask and another portion of the particles adhere to the mask, separating the mask containing the hard particles adhered to it from the carrier leaving the pattern of the particles on the carrier, at least partially surrounding the particles on the carrier with a retaining matrix material, and heating the retaining matrix material to cause the material to form a retaining matrix that holds the particles in the pattern.
[origin: WO0143918A2] A method for making an abrasive material comprising a plurality of hard particles (75) providing the abrasive quality distributed in a retaining matrix for holding the particles in place, the method comprising the steps of placing a mask (50) having openings therein against a carrier (75) capable of supporting a plurality of the particles, providing an affixing capability to an outer side of the mask remote from the carrier to which hard particles will adhere, applying a plurality of hard particles to the outer side of the mask so that a portion of the particles pass through the openings of the mask and form a pattern of the particles on the carrier corresponding to the openings of the mask and another portion of the particles adhere to the mask, separating the mask containing the hard particles adhered to it from the carrier leaving the pattern of the particles on the carrier, at least partially surrounding the particles on the carrier with a retaining matrix material, and heating the retaining matrix material to cause the material to form a retaining matrix that holds the particles in the pattern.

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